

# Ion Milling System ArBlade 5000

The most advanced ion milling system for producing exceptionally high-quality cross-section or flat-milling samples for electron microscopy.

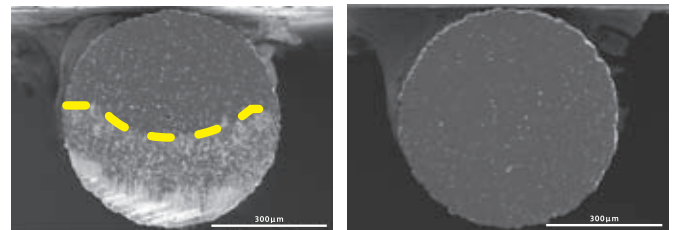


## Feature

- Cross-section milling rate : 1 mm/hour !** ※1  
Milling rate greatly improved by high current density of the ion beam. ※2

※1 This rate is the maximum depth processed for 1 hour when Si is protruded 100 μm from the mask edge.

※2 Milling rate is two times greater than that of Model IM4000Plus.

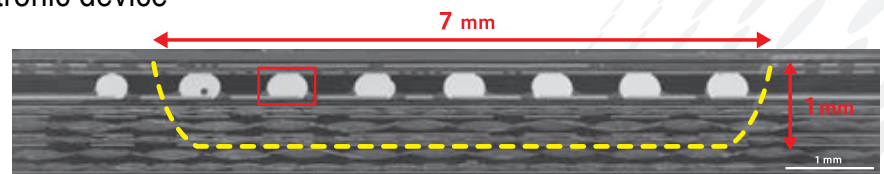


IM4000PLUS

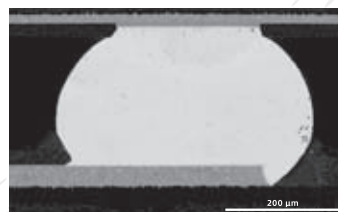
ArBlade 5000

Comparison of cross-section milling  
(Specimen : lead for mechanical pencil, Milling time : 1.5 hours)

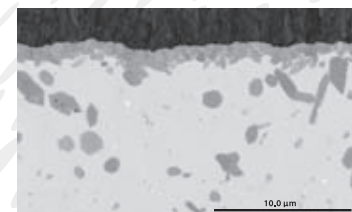
- Cross-section widths up to 8 mm !**  
It is possible to expand milling width up to 8 mm with the wide area cross-section milling function. The function is suitable for electronic device samples.



- Hybrid Model**  
The ArBlade 5000 is the latest hybrid ion-milling system, in the Hitachi Argon Ion Milling System family of preparation equipment [IM4000 + systems].



Enlarged of the red frame



Enlarged of the left image

Example of wide-area cross-section milling  
(Specimen : electronic component, Milling time : 5 hours)

